IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

n re Application of:)
Gaku MINAMIHABA et al.	Group Art Unit: 2818
Application No. 10/771,060	Examiner: Goodwin, David J.
Filed: February 4, 2004) Confirmation No.: 2231
For: POLISHING PAD AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICES)))
Mailstop Amendment	

Mailstop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

AMENDMENT

In reply to the Office Action mailed October 31, 2007, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper.

Remarks/Arguments are set forth on this paper beginning on page 5.

An Attachment to this paper is Appendix A containing title page, copyright page, and pages 120-121 of the Planarization Technical Term Dictionary.